



1/9

FIG. 1

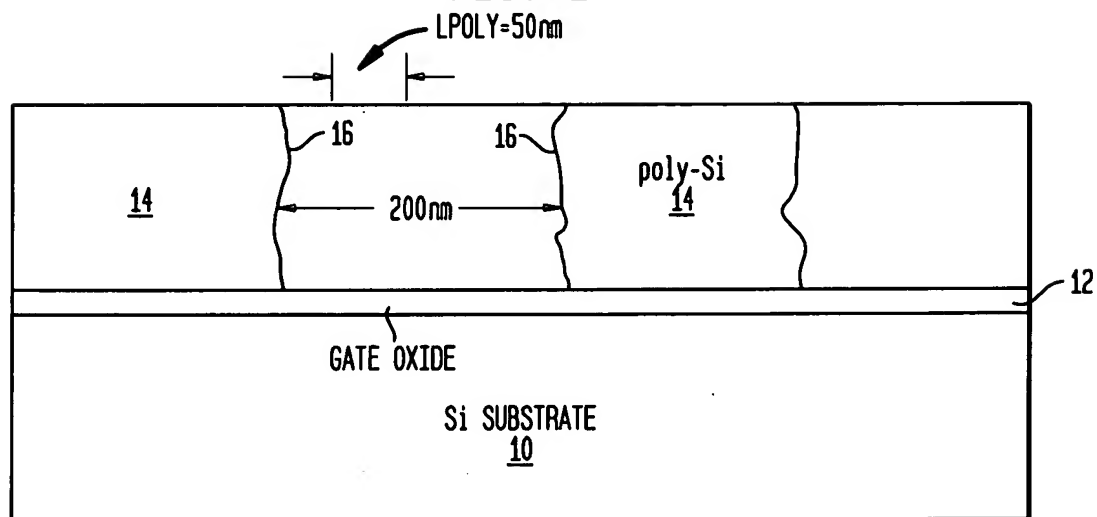


FIG. 2

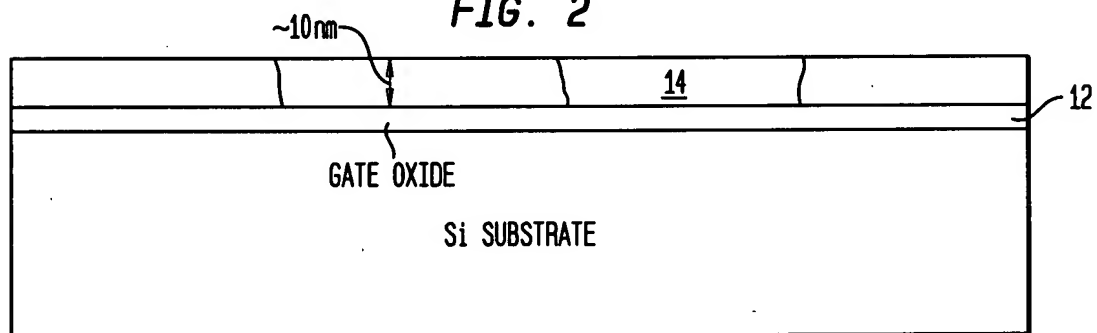


FIG. 3

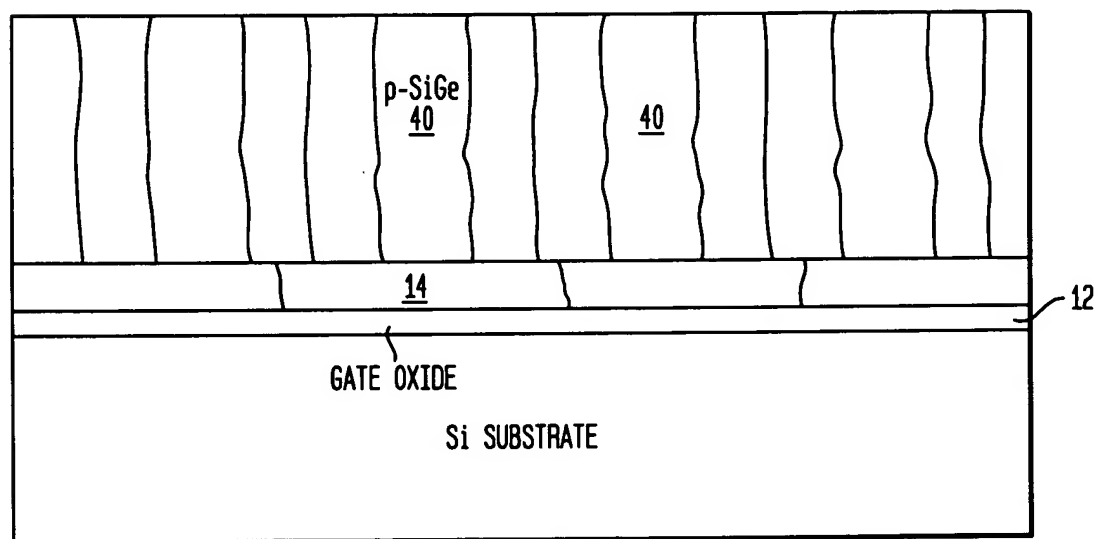
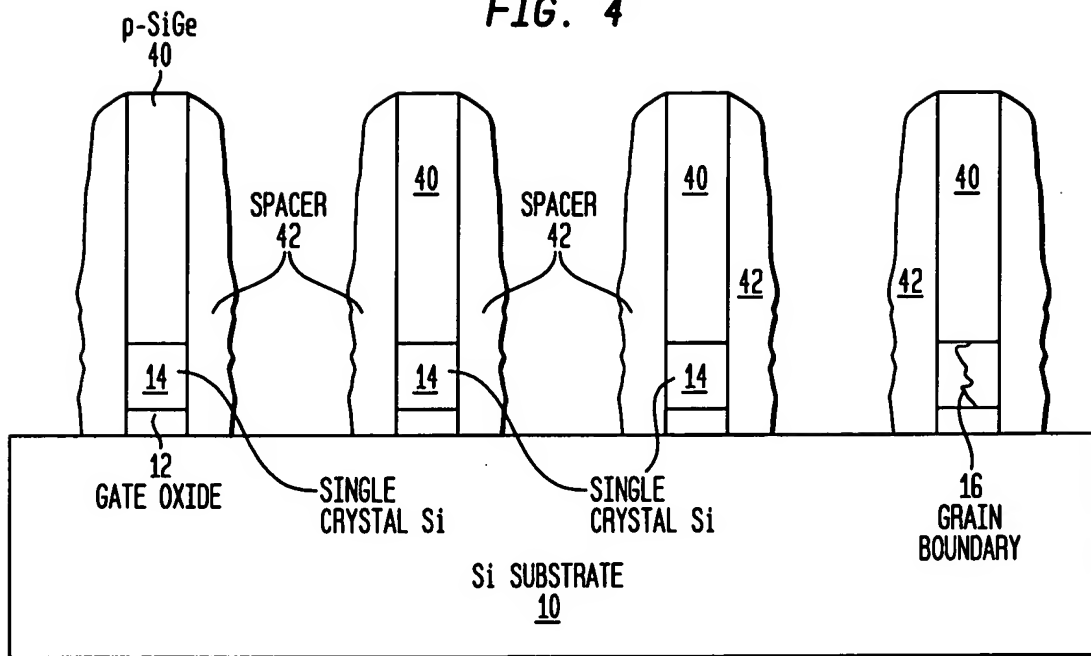
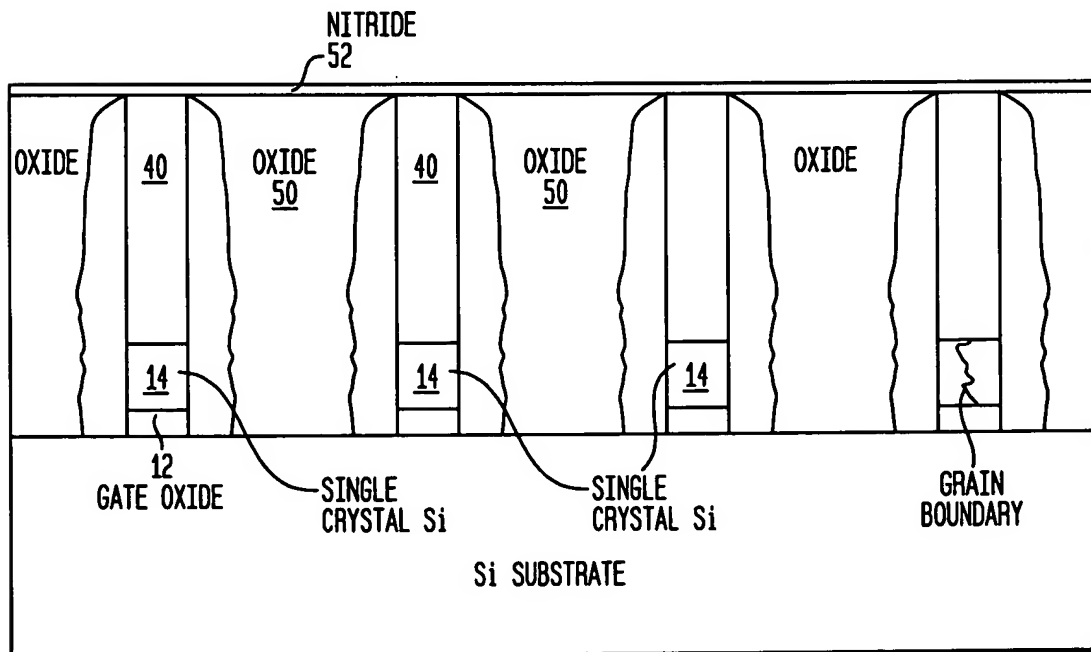


FIG. 4**FIG. 5**

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FIG. 6

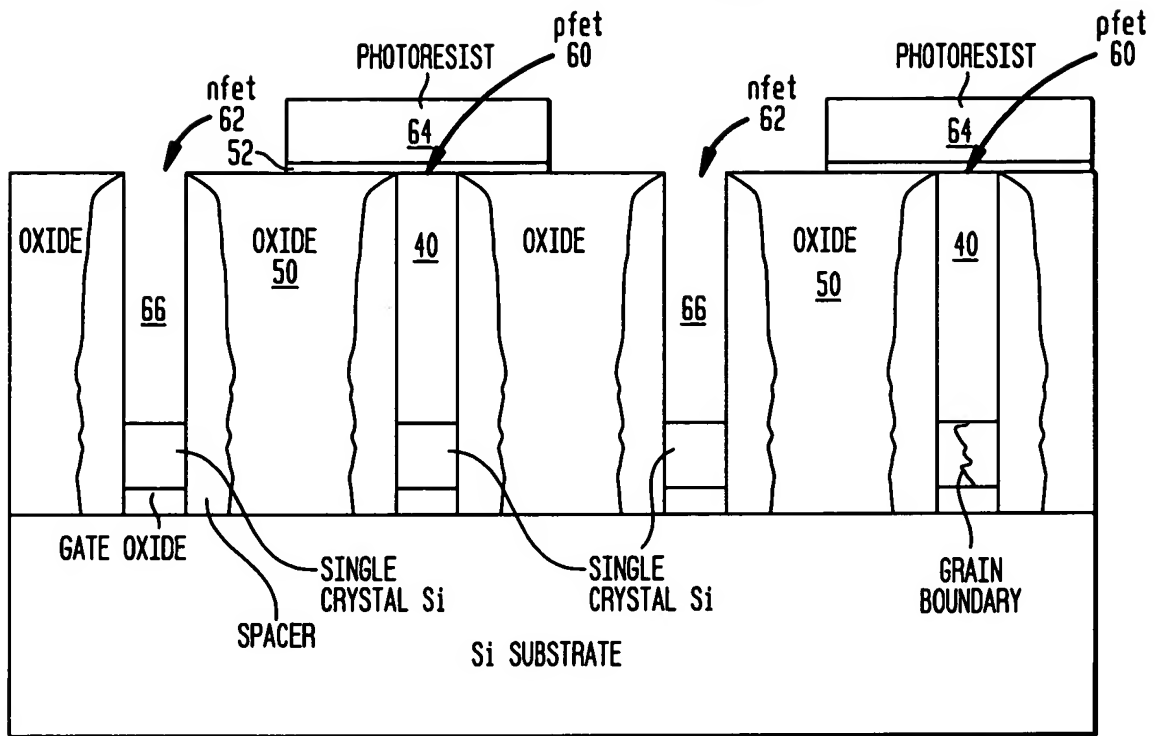
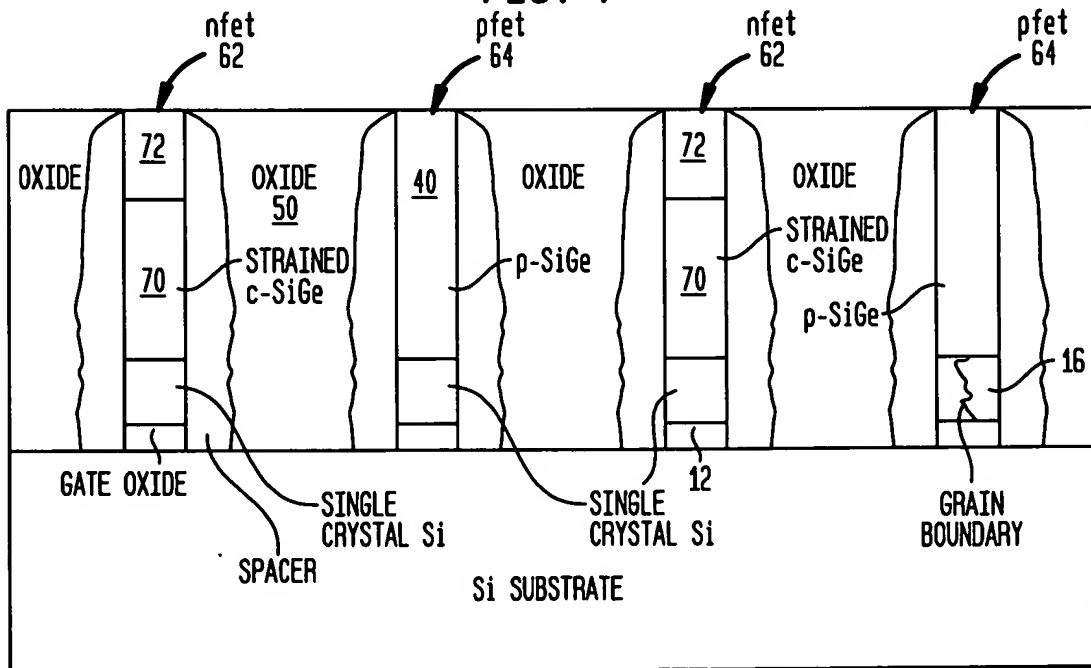
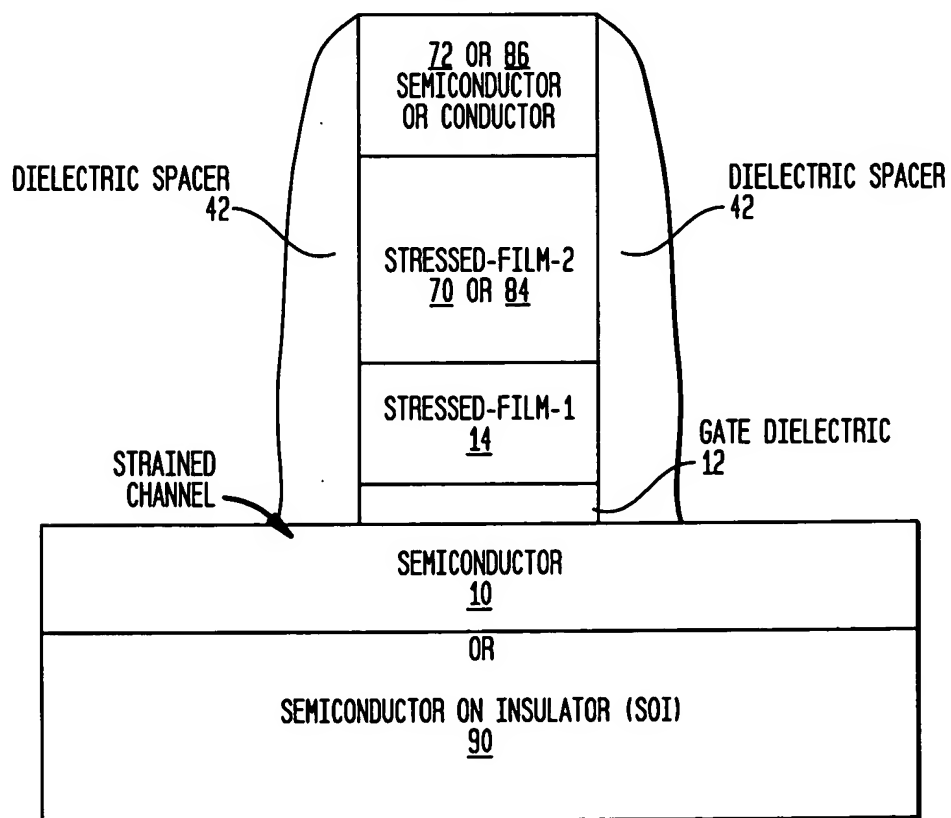


FIG. 7





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FIG. 10

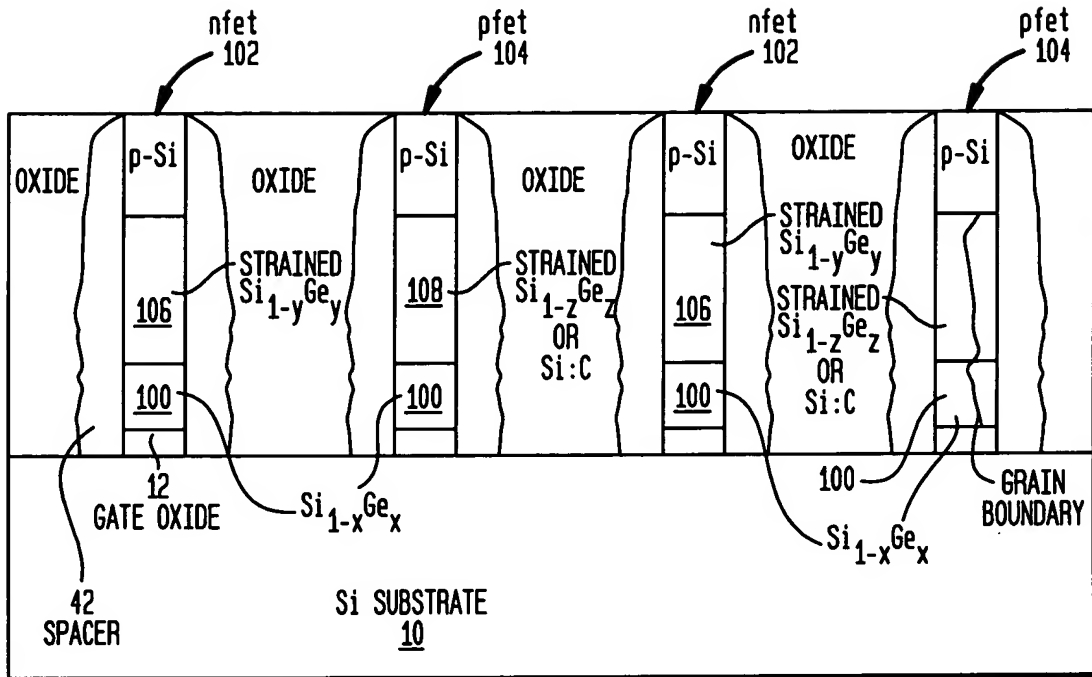
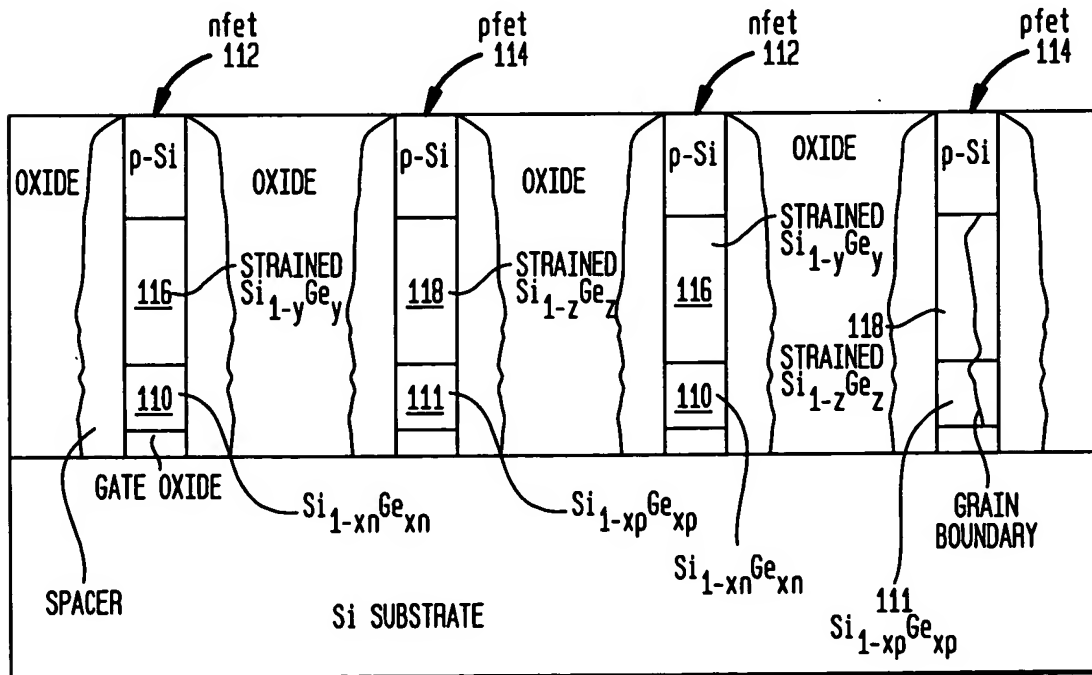


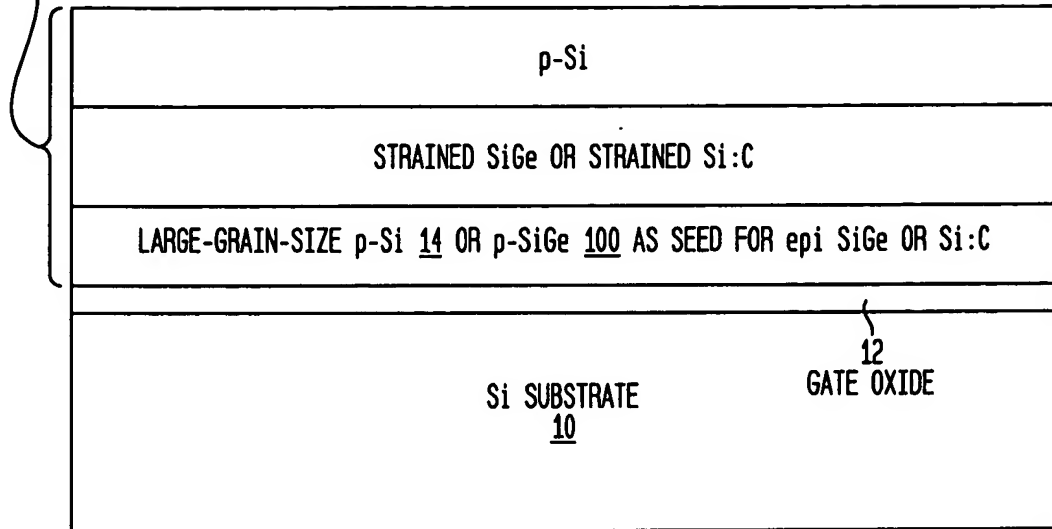
FIG. 11



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FIG. 12GATE
STACKED-LAYER
120

SCHEMATIC OF LAYER STRUCTURE BEFORE GATE PATTERNING

**FIG. 13**

BONDED OXIDE/Si INTERFACE

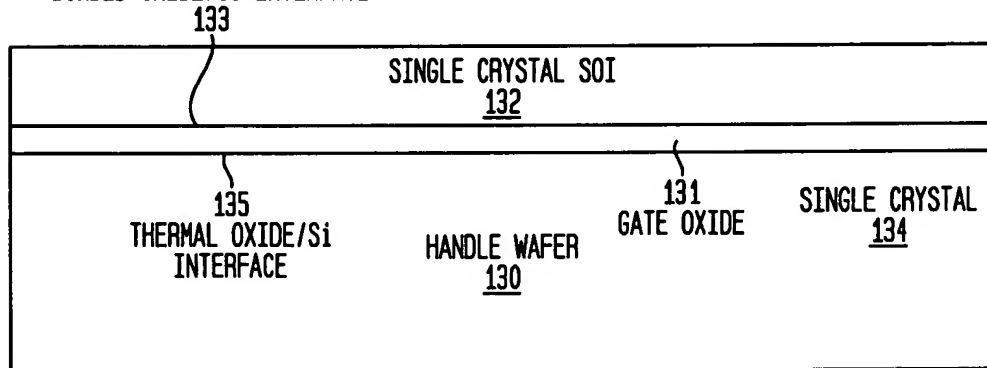
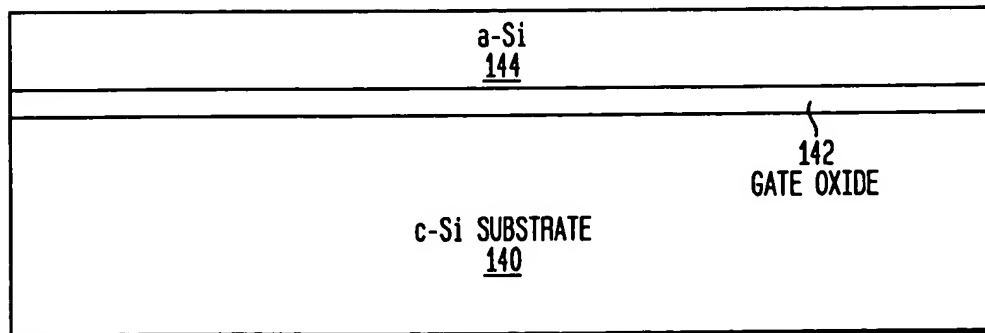
**FIG. 14**

FIG. 15

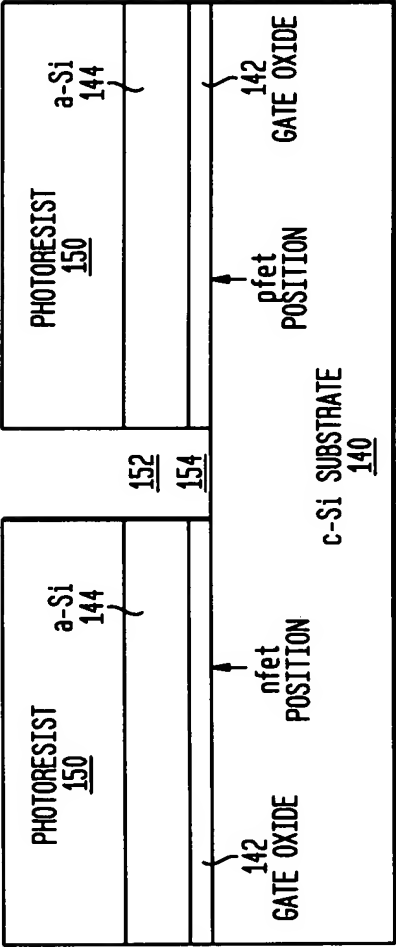


FIG. 16

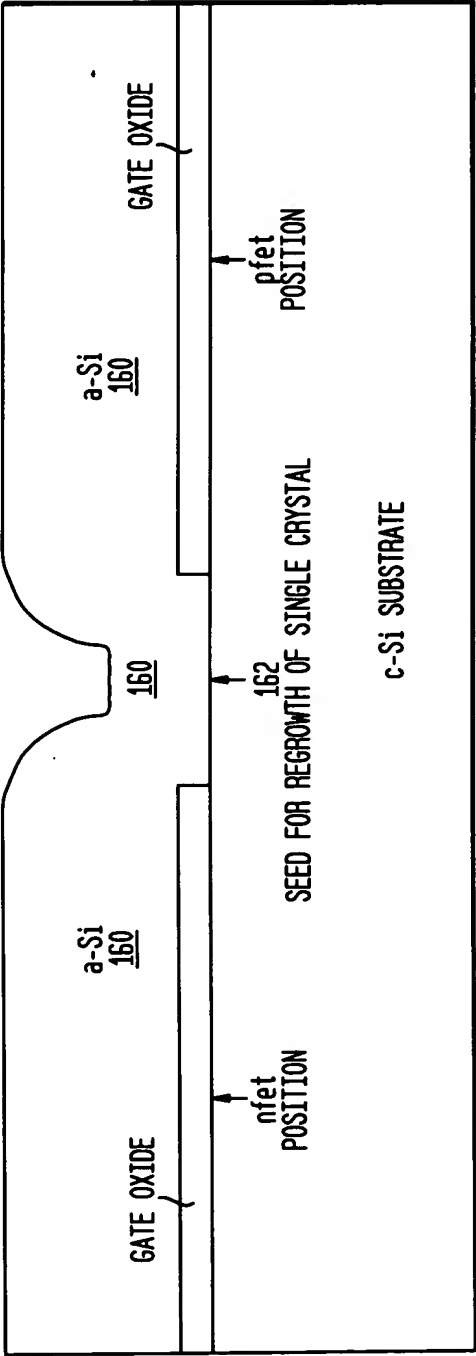


FIG. 17

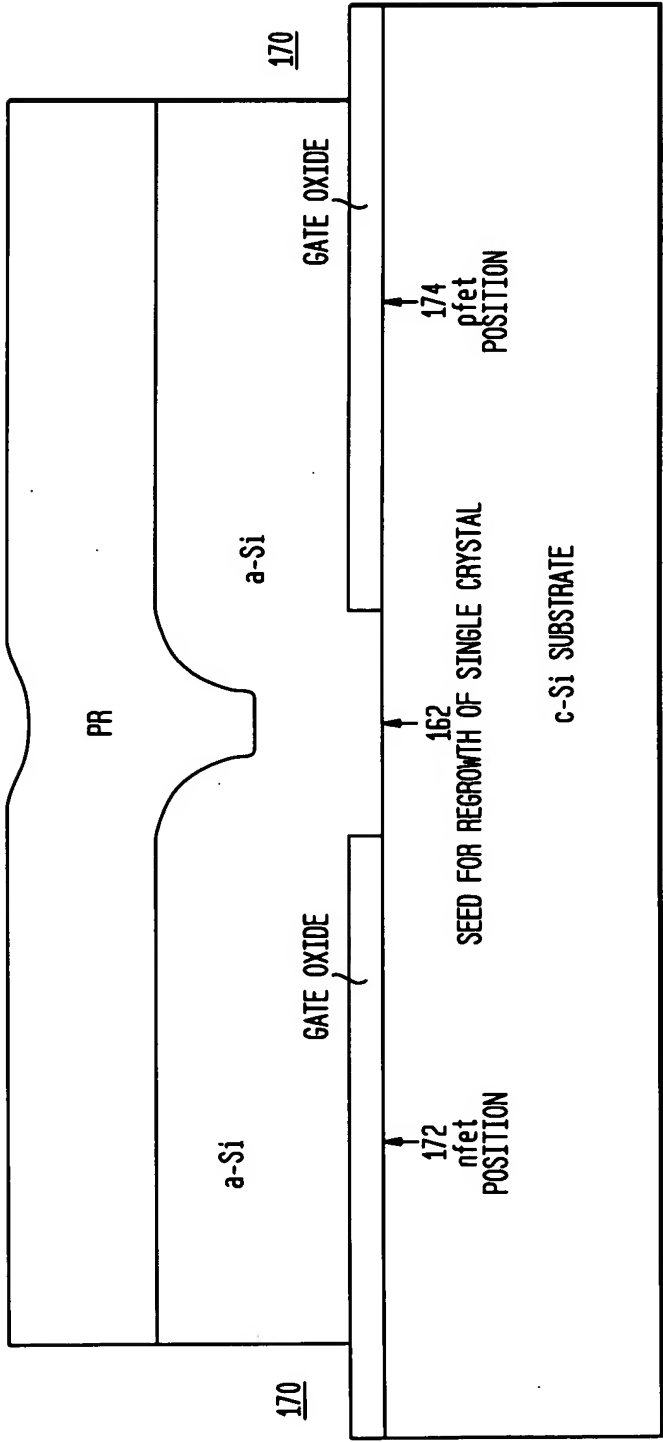


FIG. 18

